

Fraunhofer Institute for Electron Beam and Plasma Technology FEP

EMO

Laboratory coater with electron beam evaporator

Coating of Metal Sheets and Strips, Energy Technologies

We deal with large-area vacuum coating of metallic plates and strips with high deposition rates. In addition to the environmental friendliness applied for conventional surface modification. of our process, another advantage is the almost

inexhaustible range of layer materials that can be used which far exceeds the materials that can be

Coating of Parts

We coat 3-dimensional objects made of metal, ceramics, or glass in order to adapt their surface properties and so improve their functionality and service life. Using vacuum coating technologies such as sputtering technology, plasmaactivated high-rate deposition, and high-rate plasma-enhanced chemical vapor deposition

(PECVD), we improve the resistance of tools and components to corrosion, scratching, and abrasion. Decorative features, demanding optical properties, biofunctionality, and biocompatibility can also be achieved by applying suitable layers and multilayer systems.

Contact

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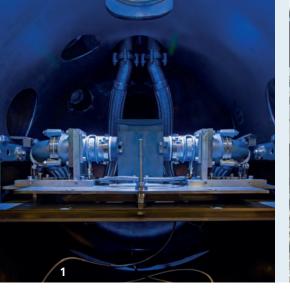
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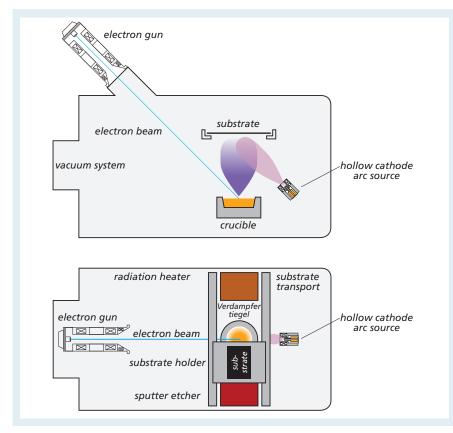
Electron beam laboratory coater EMO



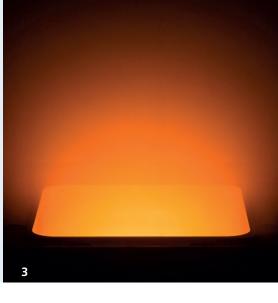


Technical specifications

Electron gun	120 kW / 40 kV
Plasma activation	Hollow cathode arc sources (HAD process)
	Spotless arc activated deposition up to 1000 A (SAD process)
Crucibles	Water-cooled copper crucible
	Hot crucible (graphite, ceramics)
Substrate size (sheets)	max. 100 mm × 200 mm
Substrate speed	up to 0.1 m/s
Additional equipment	Radiation heater max. 4 kW
	Plasma etcher max. 3 kW
	DC magnetron max. 5 kW



Scheme



Technologies

Coating processes:

- High-rate electron beam evaporation
- Thermal evaporation of sublimating materials
- Plasma-activated deposition processes (HAD and SAD process)
- Magnetron sputtering
- Magnetron PECVD process for sheets

Pre-treatment and post-treatment:

- Heating
- Plasma pre-treatment
 - Magnetron sputter etching
 - Hollow cathode plasma pre-treatment
- Interfacial layers

Electron beam melting

Test of key components for electron beam technology

Process control:

- Substrate temperature measurement
- Computer-based data logging

- 2 Transport system and evaporation unit
- **3** Vacuum chamber during a process



We focus on quality and the ISO 9001.



¹ View into the vacuum chamber